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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Applicant:

Joseph M. Steigerwald

Serial No.: 10/722,801

Filed: November 26, 2003

For: Electrochemically Polishing Conductive  
Films on Semiconductor Wafers

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Art Unit: 2815

Examiner: Sheila V. Clark

Atty Docket: ITL.0947US  
P15971

Mail Stop **Amendment**  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

**RESPONSE TO RESTRICTION REQUIREMENT**

Sir:

In response to the restriction requirement mailed July 29, 2004, please amend the above-referenced patent application as follows:

Date of Deposit: August 5, 2004

I hereby certify under 37 CFR 1.8(a) that this correspondence is being deposited with the United States Postal Service as **first class mail** with sufficient postage on the date indicated above and is addressed to the Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

*Cynthia L. Hayden*  
Cynthia L. Hayden